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Atty. Docket No. AMAT/5813/ETCH/METAL/JB

12/18/01
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IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

Box Patent Application
 Assistant Commissioner of Patents and Trademarks
 Washington, D.C. 20231

Re: Inventor(s): Melisa Buie; Brigitte Stoehr; and Guenther Ruhl
 Title: ETCH PROCESS FOR PHOTOLITHOGRAPHIC RETICLE
 MANUFACTURING WITH IMPROVED ETCH BIAS

Transmitted herewith is the patent application identified above, including:

- Specification, claims and abstract, totaling 24 pages.
- Drawings totaling 3 pages, Formal Informal.
- Executed Declaration and Power of Attorney.
- Information Disclosure Statement w/ Form 1449 and References.
- Assignment of the invention to **Applied Materials, Inc.**
- Assignment Recordation Cover Sheet

FEE CALCULATION					
Fee Items	Claims Filed	Included With Basic Fee	Extra Claims	Fee Rate	Total
Total Claims	24	-20=	4	x \$18.00	\$72.00
Independent Claims	3	-3=	0	x \$84.00	\$84.00
Basic Filing Fee		\$740.00		\$740.00	
TOTAL FEES					\$896.00

- The Commissioner is hereby authorized to charge \$896.00 to Deposit Account No. 50-1074/AMAT/5813/ETCH/METAL/JB.
- The Commissioner is hereby authorized to charge any additional fees which may be required, or credit any overpayment to Deposit Account No. 50-1074/5813/ETCH/METAL/JB. A duplicate copy of this transmittal is enclosed.
- Please address all future correspondence to:

PATENT COUNSEL
APPLIED MATERIALS, INC.
 Legal Affairs Department
 P.O.BOX 450A
 Santa Clara, CA. 95052

Respectfully submitted,

Robert W. Mulcahy
 Registration No. 25,436

(713) 623-4844

I hereby certify that this correspondence is being deposited with the United States Postal Service as express mail in an envelope addressed to: Commissioner for Patents, Box Patent Application, Washington, DC 20231.

Express Mail Receipt No EV 041916383 US

Date of Deposit 12-18-01

Signature: 